

Progress meeting

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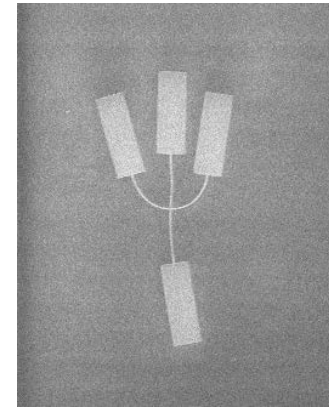
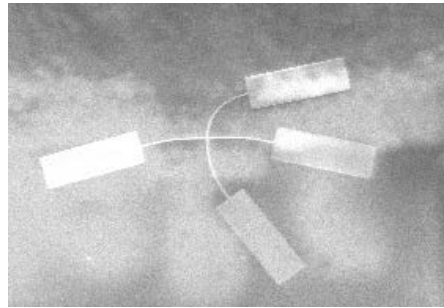
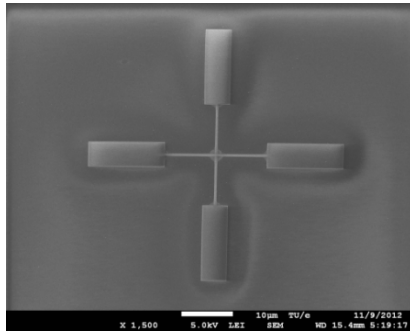
TU / **e**

Technische Universiteit
Eindhoven
University of Technology

Where innovation starts

Reproducibility

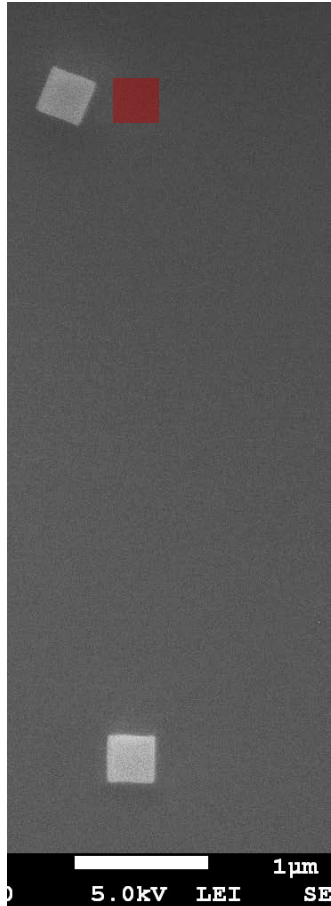
- EBL mark with same dose



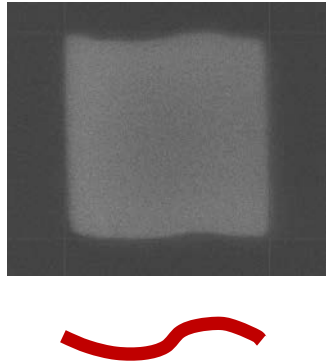
Low reproducibility
due to poor adhesion
of photoresist (hsq)

Other proofs of adhesion problems

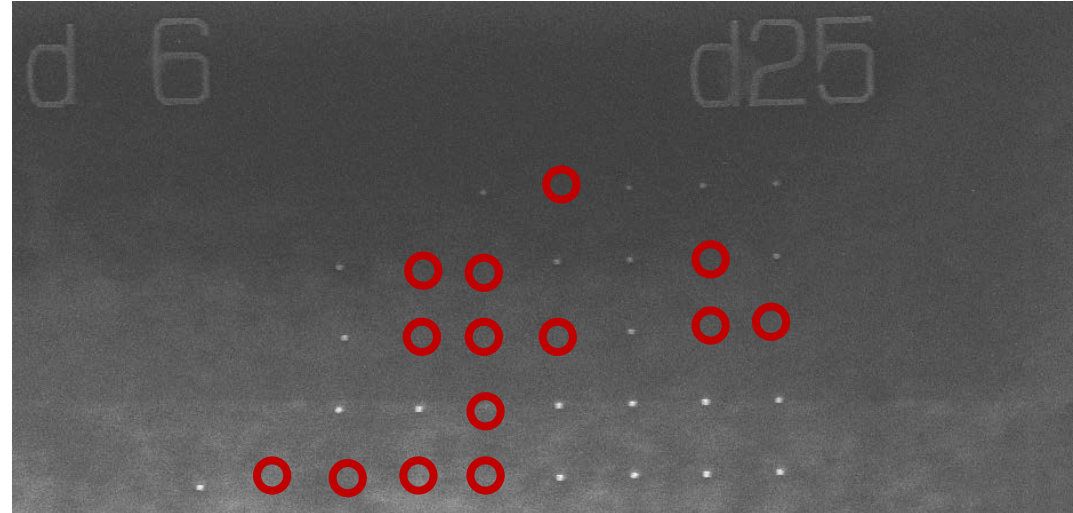
Displacement and rotation



Wavy features



Missing structures in dose test

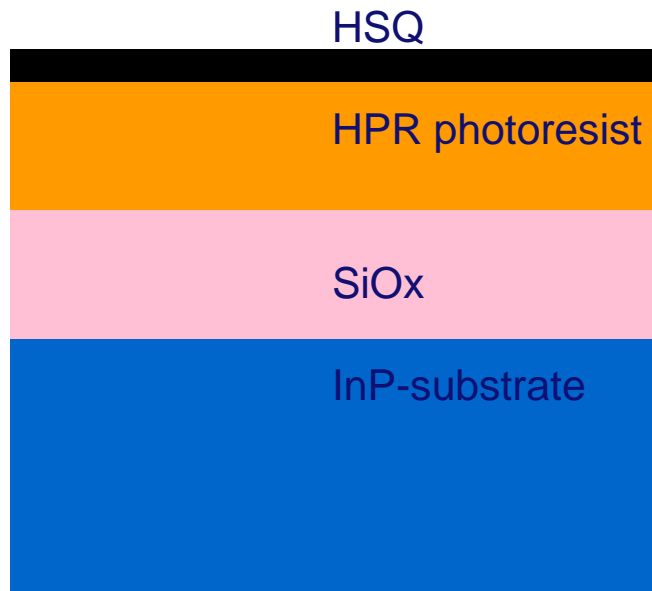


Dose factor

Dose: 100 $\mu\text{C}/\text{cm}$

Testing of a new masking scheme

- Before



- Under test



- Adhesion ✓
- Transferred roughness ?